



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Stefan Fliss Art Unit: Unknown Serial No.: 10/660,790 Examiner: Unknown

Filed: September 12, 2003

Title : APPARATUS FOR MONITORING THE FUNCTIONALITY OF AN OPTICAL

**ELEMENT** 

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Copies of the references listed on the attached form PTO-1449 are enclosed. A copy of a communication from a foreign patent office in a counterpart application is also enclosed.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 0/8/03

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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 15540-011001	Application No 10/660,790		E Je
Inf rmati n Disclosure Statement by Applicant (Use several sheets if necessary)  (37 CFR §1.98(b))		Applicant Stefan Fliss		OCT 0 8	2003
		Filing Date September 12, 2003	Group Art Unit	TELL BADE	MARK

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,691,106	Sept. 1, 1987	Hyun et al.			

Other Documents (include Author, Title, Date, and Place of Publication)			
Examiner Initial	Desig. ID	Document	
	AB	Dowden, S. et al., "Reflectometer for fast measurements of mirror reflectivity," Measurement Science and Technology, IOP Publishing, Bristol, GB, Bd. 8, Nr. 11, pp. 1258-1261 (1997).	
	AC	Takahashi H. et al., "Automatic reflectivity map measurement of high power CO <sub>2</sub> laser optics," Optics and Laser Technology, Elsevier Science Publishers BV., Amsterdam, NL, Bd. 21, Nr. 1, pp. 37-39 (1989).	

Examiner Signature Date Considered

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.